

NOV 21 2005

PATENT

Atty. Dkt. No. APPM/007034.P1/DSM/LOW KJW

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:  
Yim, et al.

Serial No.: 10/773,060

Confirmation No.: 5473

Filed: February 4, 2004

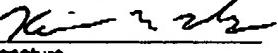
For: Ultra Low Dielectric Materials  
Based on Hybrid System of Linear  
Silicon Precursor and Organic  
Porogen by Plasma-Enhanced  
Chemical Vapor Deposition  
(PECVD)

MAIL STOP AF  
Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Dear Sir:

§ Group Art Unit: 1762

§ Examiner: Marianne L. Padgett

CERTIFICATE OF FACSIMILE TRANSMISSION UNDER 37 CFR 1.8	
<p>I hereby certify that this correspondence and the documents referred to as attached therein are being facsimile transmitted to the U.S. Patent and Trademark Office to the fax number indicated by the Examiner, namely, fax number (571) 273-8300 to the attention of the named Examiner, on the date below.</p>	
11/21/05	
Date	Signature

## SECOND RESPONSE TO FINAL OFFICE ACTION DATED AUGUST 26, 2005

In response to the Final Office Action dated August 26, 2005, having a shortened statutory period for response set to expire on November 26, 2005, please enter this response and reconsider the claims pending in the application for reasons discussed below. The Commissioner is hereby authorized to charge counsel's Deposit Account No. 20-0782/APPM/007034.P1/KMT for any fees, including extension of time fees or excess claim fees, required to make this response timely and acceptable to the Office.

**Amendments to the Claims** are listed beginning on page 2 of this paper.  
**Remarks** begin on page 5 of this paper.